

## Japan Gases & Facilities Committee Meeting Summary and Minutes

**SEMI Japan Standards Fall 2013 Meetings**  
Friday, September, 27, 2013, 15:00-17:00  
SEMI Japan, Tokyo, Japan

### Next Committee Meeting

Tuesday, December 5, 2012, 14:00-17:00  
SEMICON Japan 2013, Makuhari Messe, Chiba, Japan

### Table 1 Meeting Attendees

**Co-Chairs:** Isao Suzuki (MKS Japan)

**SEMI Staff:** Naoko Tejima (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Swagelok	Ishida	Noritsugu	Algo System	Ogihara	Hideaki
HORIBA STEC	Isobe	Yasuhiro	Tokyo Electron Tohoku	Okabe	Tsuneyuki
Fujikin	Machii	Yoshifumi	HORIBA STEC	Shimizu	Tetsuo
ACE	Mihira	Hiroshi	MKS Japan	Suzuki	Isao
Tokyo Electron Yamanashi	Moriya	Shuji	SEMI Japan	Naoko	Tejima

*\* alphabetical order by last name*

### Table 2 Leadership Changes

None

### Table 3 Ballot Results

None

### Table 4 Authorized Ballots

#	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>
TBD	C1-14	5-year-review Task Force	Reapproval of SEMI F80-0309, Test Method for Determination of Gas Change/Purge Efficiency of Gas Delivery System (with Editorial Changes).

### Table 5 Authorized Activities

#	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
TBD	SNARF	5-year-review Task Force	Reapproval of SEMI F80-0309, Test Method for Determination of Gas Change/Purge Efficiency of Gas Delivery System (with Editorial Changes).

**Table 6 New Action Items**

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
G+F130628-01	Hirromichi Enami Isao Suzuki	To prepare for a small workshop / an enlarged committee meeting regarding the measurement of the small particles in the gas components and systems at SEMICON Japan 2013 (December 5). <ul style="list-style-type: none"> <li>• Invite some speakers from a device manufacturer, a measurement equipment manufacturer or a University.</li> </ul>
G+F130927-01	SEMI staff	To prepare SNARF and SEMI F80 Reapproval ballot for Cycle 1, 2014.
G+F130927-02	Standardization of Live Gas Flow Rate Study Group	To survey about calibration of Live Gas Flow Rate will be made to Mass Flow Manufacturers.

## 1 Welcome, Reminders and Introductions

Isao Suzuki, committee co-chair, called the meeting to order at 15:00. Self-introductions were made followed by the agenda review.

## 2 Required Meeting Elements

The meeting reminders on program membership requirement, antitrust issues, intellectual property issues and international effective meeting guidelines, were reviewed by SEMI staff, Naoko Tejima.

## 3 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on June 28, 2013.

**Motion:** To approve the minutes of the previous meeting as written.

**By / 2<sup>nd</sup>:** Hiroshi Mihira (ACE) / Noritsugu Ishida, (Swagelok)

**Discussion:** None

**Vote:** 7 in favor and 0 opposed. **Motion passed.**

**Attachment:** 01\_JA\_G+F\_Previous\_Mtg\_Minutes\_130927

## 4 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2013 Calendar of Events, Global Standards Meeting Schedule, SEMICON Europa Standard Meeting Schedule, NA Standards Fall 2013 Meetings, 2013 Critical Dates for SEMI Standards Ballots, SEMI Standards Publication, SEMICON Japan 2013 Information and Contact Information.

**Attachment:** 02\_SEMI\_Staff\_Report\_130927

## 5 Liaison Reports

### 5.1 North America Facilities and Gases Committee

Naoko Tejima briefly reported for the North America Facilities and Gases Committee. This report included Leadership, Current Committee Organization, Meeting Information, New SNARFs, Ballot Results Summary, Upcoming Ballots for Cycle 5 & 6, 2013, Subcommittee and Task Force Activities Highlights and Contact Information.

**Attachment:** 03\_NA\_Facilities\_and\_Gases\_Comm\_Report\_130927

### 5.2 Europe Gases and Liquid Chemicals Committee

No report was provided.

### 5.3 Korea Facilities Committee

No report was provided.

## 6 Task Force Reports

### 6.1 F1 Revision Task Force

Yoshifumi Machii reported for the F1 Revision Task Force that there were not particular activities.

### 6.2 Gas Panel and Metal Seal Test Methods Task Force

Shuji Moriya reported for the Gas Panel and Metal Seal Test Methods Task Force that there were not particular activities.

### 6.3 5-year-review Task Force

Yoshifumi Machii reported for the 5-year-review Task Force. The Task Force met earlier in the day. Of note:

- SEMI F80-0309, Test Method for Determination of Gas Change/Purge Efficiency of Gas Delivery System is due for 5-year-review. The Task Force agreed to submit reapproval ballot for Cycle 1, 2014.

**Motion:** To approve a new SNARF to reapprove SEMI F80-0309  
**By / 2<sup>nd</sup>:** Yoshifumi Machii (Fujikin) / Noritsugu Ishida, (Swagelok)  
**Discussion:** None.  
**Vote:** 8 in favor and 0 opposed. **Motion passed.**

**Motion:** To submit SEMI F80-0309 Reapproval ballot for Cycle 1, 2014.  
**By / 2<sup>nd</sup>:** Yoshifumi Machii (Fujikin) / Noritsugu Ishida, (Swagelok)  
**Discussion:** None.  
**Vote:** 8 in favor and 0 opposed. **Motion passed.**

**Action Item:** SEMI staff to prepare SNARF and SEMI F80 Reapproval ballot for Cycle 1, 2014.

**Attachment:** 04\_SNARF\_of\_SEMI-F80\_130927

### 6.4 Standardization of Live Gas Flow Rate Study Group

Shuji Moriya reported for the Standardization of Live Gas Flow Rate Study Group. The Study Group met earlier in the day. Of note:

- Explanation of the background why Standardization of Live Gas Flow Rate is required was made, and how the gas is calibrated was presented.
- Since the discussion about all type gases together is difficult, they are divided into 3, (1) the general-purpose gases, (2) the general-purpose liquid materials, (3) the new liquid materials, and will be discussed in stages.
- The survey about calibration of Live Gas Flow Rate will be made to Mass Flow Manufacturers (HORIBA STEC, Fujikin, MKS, Brooks Instrument, Hitachi Metals and so on), referring to the *SEMI E52-0912, Practice for Referencing Gases, Gas Mixtures and Vaporizable Materials used in Digital Mass flow Controllers*.
- The result of the survey will be discussed at the next meeting

**Action Item:** SG to survey about calibration of Live Gas Flow Rate will be made to Mass Flow Manufacturers.

## 7 Old Business

### 7.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

**Table 7** Previous Meeting Actions Items

Item #	Assigned to	Details
G+F130628-01	Hikomichi Enami Isao Suzuki	To prepare for a small workshop / an enlarged committee meeting regarding the measurement of the small particles in the gas components and systems at SEMICON Japan 2013 (December 5). <ul style="list-style-type: none"> <li>Invite some speakers from a device manufacturer, a measurement equipment manufacturer or a University. ... <b>Open</b></li> </ul>

## 8 New Business

### 8.1 Explanation about the situation of EtherCAT

Hideaki Ogihara explained about the situation of EtherCAT. Of note:

While SEMI Standards developed SEMI E54.20 “Standard for Sensor/Actuator Network Communications for EtherCAT” , the Semiconductor Profile Technical Working Group (Semi-profile TWG) of the EtherCAT Technology Group (ETG) supposed to publish the ETG document for SEMI specific device profiles at their meeting on October 15-16. According to the requests by the semiconductor manufactures involving to G450C, the equipment for 450 mm with EtherCAT might be popular. On the other hand, the information on Semi-profile TWG and its activity is not publicly provided, their activity has not commonly known yet.. It might be necessary for us to get that information and share at the Japan Sensor Bus Task Force.

Gases & Facilities committee asked Mr. Ogihara to update about the EtherCAT situation, at the next committee meeting.

## 9 Action Item Review

### 9.1 *New Action Items*

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

## 10 Next Meeting and Adjournment

The next meeting of the Japan Gases & Facilities Committee is scheduled for Wednesday, December 4, 2013, 14:00-17:00, in conjunction with SEMICON Japan 2013, Makuhari Messe, Chiba, Japan.

Prior to the Committee meeting, 5 year-review Standardization of Live Gas Flow Rate Study Group will be held on the same day.

Respectfully submitted by:  
Naoko Tejima  
Manager, Standards  
SEMI Japan  
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Email: ntejima@semi.org

Minutes approved by:

Isao Suzuki (MKS Japan), Co-chairs	October 30, 2013
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**Table 8 Index of Available Attachments #1**

#	<i>Title</i>
1	JA_G+F_Previous_Mtg_Minutes_130927
2	SEMI_Staff_Report_130927
3	NA_Facilities_and_Gases_Comm_Report_130927
4	SNARF_of_SEMI-F80_130927

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at [www.semi.org](http://www.semi.org). For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.